

09/701534

526 Rec'd PCT/PTO 30 NOV 2000  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

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Masahiro FURUSAWA, Ichio YUDASAKA, Yasuo  
MATSUKI, Yasumasa TAKEUCHI

Application No.: U.S. National Stage of PCT/JP00/01987

Filed: November 30, 2000

Docket No.: 107291

For: METHOD FOR FORMING SILICON FILM AND INK COMPOSITION FOR INK JET

INFORMATION DISCLOSURE STATEMENT

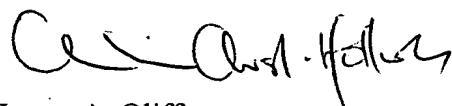
Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- 2. The references were cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information.

Respectfully submitted,



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